

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **Confirmation No. 1632**
Norio KIMURA et al. : Attorney Docket No. 2001-0660A
Serial No. 09/864,208 : Group Art Unit 1763
Filed May 25, 2001 : Examiner Jeffrie R. Lund
SUBSTRATE POLISHING APPARATUS : **MAIL STOP: AMENDMENT**
AND SUBSTRATE POLISHING METHOD



AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In response to the Office Action of October 4, 2005, the period for response to which having been extended by two months to March 4, 2006, kindly amend the above-referenced U.S. patent application as follows:

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975